



Image 2877
Attorney's Docket No.: 09712-055001 / Z-200 *#*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Art Unit : 2877
Serial No. : 10/025,595 Examiner : Hwa S. Lee
Filed : December 18, 2001
Title : OPTICAL SURFACE PROFILING SYSTEMS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF DECEMBER 17, 2003

Please amend the above-identified application as follows:

03/18/2004 JDALINAN 00000086 10025595

01 FC:1201	344.00 OP
02 FC:1202	90.00 OP

Please replace the Description of the Drawings at page 8 with the following amended Description of the Drawings:

Fig. 1 is a schematic representation of an interferometric surface profiler;

Fig. 2 is a plot of interference intensity as a function of scan position;

Fig. 3A and 3B are schematic representations comparing the resolution of a typical imaging interferometer and an interferometer including a lenslet array; ~~and~~

Fig. 4 is a schematic representation of ~~another~~ a second embodiment of an interferometric surface profiler;

Fig. 5 is a schematic representation of a third embodiment of an interferometric surface profiler; and

Fig. 6 is a schematic representation of a fourth embodiment of an interferometric surface profiler.

Like reference symbols in the various drawings indicate like elements.

Please add the following new paragraphs after the paragraph ending at page 13, line 26:

Referring to Fig. 5, an interferometric optical profiler 100' includes a detector optical imaging system 151 and a lenslet array 110' comprising an array of elements each providing focusing power through diffraction.

Referring to Fig. 6, an interferometric optical profiler 100'' includes a detector optical imaging system 151' and a lenslet array 110'' comprising an array of elements each providing focusing power through reflection.